



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Liming Tsau

Appl. No.: 10/750,834

Filed: October 7, 2004

For: **High Density Metal Capacitor
Using Via Etch Stopping Layer as
Field Dielectric in Dual-
Damascene Interconnect Process**

Confirmation No.: 2507

Art Unit: 2823

Examiner: Khiem D. Nguyen

Atty. Docket: 1875.0230001

Amendment and Reply Under 37 C.F.R. § 1.111

Commissioner for Patents
Mail Stop Amendment
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated January 21, 2005, Applicant submits the following Remarks.

It is not believed that extensions of time or fees for net addition of claims are required beyond those that may otherwise be provided for in documents accompanying this paper. However, if additional extensions of time are necessary to prevent abandonment of this application, then such extensions of time are hereby petitioned under 37 C.F.R. § 1.136(a), and any fees required therefore (including fees for net addition of claims) are hereby authorized to be charged to our Deposit Account No. 19-0036.